Docket No.

251598US0

IN RE APPLICATION OF: Yukio HOSAKA, et al

SERIAL NO: 10/820,123

FILED:

April 8, 2004

FOR:

ABRASIVE PAD, METHOD AND METAL MOLD FOR MANUFACTURING THE SAME, AND

SEMICONDUCTOR WAFER POLISHING METHOD

COMMISSIONER FOR PATENTS ALEXANDRIA, VIRGINIA 22313

Transmitted herewith is an amendment in the above-identified application.

- ☐ No additional fee is required
- ☐ Small entity status of this application under 37 C.F.R. §1.9 and §1.27 is claimed.
- ☐ Additional documents filed herewith:

The Fee has been calculated as shown below:

CLAIMS	CLAIMS REMAINING		HIGHEST NUMBER PREVIOUSLY PAID	NO. EXTRA CLAIMS		RATE		CALCULATIONS
TOTAL	21	MINUS	20	1	х	\$50	=	\$50.00
INDEPENDENT	1	MINUS	3	0	х	\$200	=	\$0.00
APPLICATION SIZE		MINUS	100	0 (each addtl. 50 sheets)	x	\$250	#	\$0.00
		☐ MULTIPLE DEPENDENT CLAIMS + \$360 =					\$0.00	
TOTAL OF ABOVE CALCULATIONS						\$50.00		
		☐ Reduction by 50% for filing by Small Entity				\$0.00		
E C						ТОТ	AL	\$50.00

- \square A check in the amount of **\$0.00** is attached.
- Credit card payment form is attached to cover the fees in the amount of \$50.00
- Please charge any additional Fees for the papers being filed herewith and for which no check or credit card payment is enclosed herewith, or credit any overpayment to deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.
- If these papers are not considered timely filed by the Patent and Trademark Office, then a petition is hereby made under 37 C.F.R. §1.136, and any additional fees required under 37 C.F.R. §1.136 for any necessary extension of time may be charged to Deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.

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IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF

:

YUKIO HOSAKA, ET AL.

: EXAMINER: RACHUBA, M.T.

SERIAL NO: 10/820,123

FILED: APRIL 8, 2004

: GROUP ART UNIT: 3723

FOR: ABRASIVE PAD, METHOD AND METAL MOLD FOR MANUFACTURING THE SAME, AND SEMICONDUCTOR

WAFER POLISHING METHOD

<u>AMENDMENT</u>

COMMISSIONER FOR PATENTS ALEXANDRIA, VIRGINIA 22313

SIR:

In response to the Office Action dated November 16, 2006, please amend the aboveidentified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.